Highlights

N GaAs

Microwave induced transformation of defect in SiC and
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• The microwave irradiation increase interstitial defect concentration at near surface region
• Stress intensity the microwave induced defect transformation
• Microwave treatment decreases σ_n of vacancy re-
lated defects in SiC and GaAs monocrystal
 The transient acoustoelectric spectroscopy used for determining properties of defects in SiC and GaAs.
determining properties of defects in sie and GaAs.
 A microwave annealing of defects in SiC and GaAs was observed.

Microwave induced transformation of defect in SiC and GaAs

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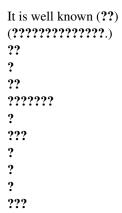
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Abstract

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Keywords: Microwave, SiC, GaAs, Defect transformation

1. Introduction



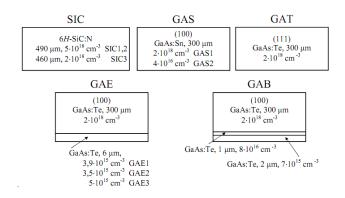


Figure 1: Structure of samples

2. Experimental details

????? ????
$$V_{\text{TAV}}(t) = V_{\text{TAV},0} \exp(-t/\tau). \tag{1}$$

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$$\tau = \frac{1}{\sigma_n \, \nu_{\text{th},n} \, N_c} \exp\left(\frac{E_c - E_t}{kT}\right). \tag{2}$$

where $v_{\text{th},n}$ is the electron thermal velocity N_C is the densities of states in the conduction band.

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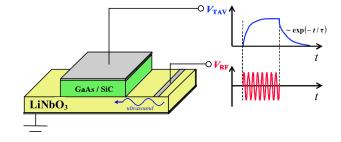


Figure 2: The scheme of TAV measurement. The time dependencies of the radio impulse $V_{\rm RF}$ for the excitation of ultrasound in a piezoelectric plate and the resulting TAV signal $V_{\rm TAV}$ are schematically shown as well.

Table 1: The determined parameters of defects in the samples n-GaAs and n-6H-SiC samples

Sample	t_{MWT} , s	Level	$(E_c - E_t)$, eV	σ_n , cm ^{2 a)}	R _{cur} , m	ξcur	
SIC1	0	ESC1	0.33 ± 0.01	$(7 \pm 4) \cdot 10^{-18}$	∞	0	
	20	ESC1	0.33 ± 0.01	$(5 \pm 3) \cdot 10^{-19}$	170.2	$8.7 \cdot 10^{-7}$	
	40	ESC2	0.26 ± 0.01	$(2 \pm 1) \cdot 10^{-19}$			
	80	weak signal					
SIC2	0	ESC1	0.33 ± 0.01	$(7 \pm 4) \cdot 10^{-18}$	> 2000	$< 1.2 \cdot 10^{-7}$	
	20	ESC1	0.33 ± 0.01	$(5 \pm 3) \cdot 10^{-19}$	171.9	$1.4 \cdot 10^{-6}$	
SIC3	0	ESC1	0.34 ± 0.02	$(3 \pm 2) \cdot 10^{-18}$	3.8	$6.1 \cdot 10^{-5}$	
	20	ESC2	0.29 ± 0.01	$(5 \pm 3) \cdot 10^{-19}$	5.5	$4.2 \cdot 10^{-5}$	
	40	ESC2	0.26 ± 0.01	$(10 \pm 7) \cdot 10^{-20}$			
	80	ESC2	0.23 ± 0.01	$(6 \pm 4) \cdot 10^{-20}$		_	
GAS1	0	EGA1	0.32 ± 0.02	$(3 \pm 2) \cdot 10^{-17}$	-53.8	$-2.8 \cdot 10^{-6}$	
	20	EGA1	0.31 ± 0.01	$(2 \pm 1) \cdot 10^{-17}$	22.9	$6.5 \cdot 10^{-6}$	
	40		weak sign			-	
GAS2	0	EGA1	0.32 ± 0.01	$(4 \pm 2) \cdot 10^{-17}$	17.2	$8.7 \cdot 10^{-6}$	
	20	EGA2	0.28 ± 0.01	$(5 \pm 2) \cdot 10^{-18}$	14.7	$1.0 \cdot 10^{-5}$	
	40		weak sign				
GAT	0	EGA3	0.49 ± 0.02	$(5 \pm 3) \cdot 10^{-14}$			
	20	EGA4	0.40 ± 0.02	$(2 \pm 1) \cdot 10^{-15}$			
GAE1	0	EGA5	0.24 ± 0.01	$(2 \pm 1) \cdot 10^{-18}$			
	60	EGA2	0.29 ± 0.01	$(10 \pm 6) \cdot 10^{-18}$			
GAE2	0	EGA5	0.25 ± 0.01	$(2 \pm 1) \cdot 10^{-18}$			
	60	EGA2	0.30 ± 0.01	$(2 \pm 1) \cdot 10^{-17}$			
GAE3	0	EGA6	0.43 ± 0.01	$(8 \pm 5) \cdot 10^{-17}$		-	
	60	EGA6	0.46 ± 0.02	$(7 \pm 4) \cdot 10^{-16}$			
GAB1	0	EGA4	0.39 ± 0.01	$(10 \pm 7) \cdot 10^{-18}$			
	20	EGA4	0.39 ± 0.01	$(4 \pm 2) \cdot 10^{-17}$			
	40	EGA6	0.43 ± 0.02	$(10 \pm 6) \cdot 10^{-17}$			
GAB2	0	EGA4	0.40 ± 0.01	$(10 \pm 6) \cdot 10^{-17}$			
	20	EGA4	0.41 ± 0.01	$(10 \pm 6) \cdot 10^{-17}$			
,	40	EGA6	0.45 ± 0.02	$(4 \pm 2) \cdot 10^{-16}$			
a) at $T = 300$ K for SIC, GA, GAE and at $T = 340$ K for GAB							

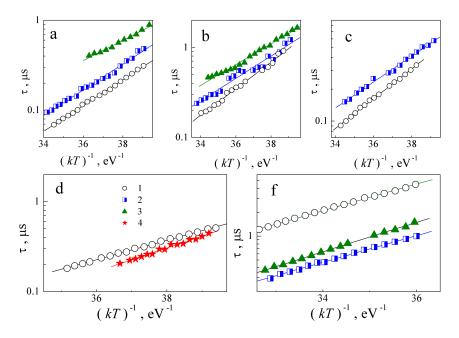


Figure 3: Dependences of TAV relaxation time on inverse temperature for samples SIC2 (a), SIC3 (b), GAS2 (c), GAE2 (d) and GAB1 (e) before and after MWT. fmt, c: 0 (curves 1), 20 (2), 40 (3), 60 (4)

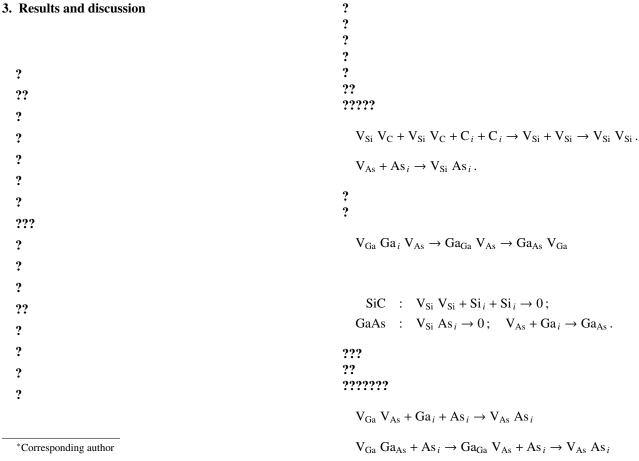


Table 2: Literature data for levels closed to the location of detected levels

$(E_c - E_t)$, eV	σ_n , cm ²	configuration	method a)	epi–structure	Reference
0.33		complex with V_{As}	$(E_c - E_t) = DLTS$	$= (0.31 \div 0.32) \text{ eV}$?
0.33	_	complex with v_{As}	DLTS	no no	;
$0.31 \div 0.33$	-	V_{As}	LDA	no	?
0.33	$1 \cdot 10^{-17}$	-	TSC	no	?
0.323	$1 \cdot 10^{-14}$	_	DLTS	yes	?
0.334	$2 \cdot 10^{-15}$		DLTS	yes	
0.35	_	complex with V _{As}	PA	no	?
$0.315 \div 0.325$	$3 \cdot 10^{-17}$	-	TSC	no	?
0.33	=	-	TSC	no	?
$0.30 \div 0.33$	-	-	DLTS	no (0.20 + 0.20) - W	?
0.20	5 10-18			$= (0.28 \div 0.30) \text{ eV}$	9
0.28	$5 \cdot 10^{-18}$	$V_{As}As_i$	TSC	no	?
0.26	$3.5 \cdot 10^{-15}$	=	DLTS	yes	?
0.277	$5 \cdot 10^{-17}$	=	TSC	no	?
0.284 0.28	$1 \cdot 10^{-17}$	intrincia	TSC TP	no	?
0.28	$8 \cdot 10^{-15}$	intrinsic	DLTS	no	
0.28	6 · 10	complex with Te	DLTS	yes no	?
0.30	$6 \cdot 10^{-15}$	$V_{As}As_i$	DLTS	no	?
0.50	0.10	$V_{As}As_i$	$A3. (E_0 - 1)$	$E_t) = 0.49 \text{ eV}$	•
0.50	_	Sb_{Ga}	DLTS	no	?
0.48	$4 \cdot 10^{-16}$	$\mathrm{As}_{\mathrm{Ga}}^{++}$	TSC	no	?
0.485	$2 \cdot 10^{-16}$	- Ga	TSC	no	?
0.48		impurity	TP	no	?
0.51	$1 \cdot 10^{-12}$	-	DLTS	no	?
0.48	$3 \cdot 10^{-13}$	-	DLTS	no	?
0.50	$1 \cdot 10^{-15}$	V_{As} , $V_{Ga}Ga_iV_{As}$	DLTS	no	?
		EGA4,	$(E_c - E_t) =$	$= (0.39 \div 0.41) \text{ eV}$	
0.42	-	-	DLTS	no	? ? ?
0.41	-	$V_{Ga}V_{As}$	DLTS	no	?
0.39	$2 \cdot 10^{-13}$	$V_{Ga}Ga_{As}$	TSC	no	
$0.41 \\ 0.40$	2 · 10 · 15	-	DLTS SCRC	yes	?
0.40	$2 \cdot 10^{-14}$	-	DLTS	yes	?
0.40	2 · 10	$V_{Ga}Ga_{As}$	DLTS	yes no	?
0.387	$2 \cdot 10^{-14}$	· Ga Gu As	DLTS	yes	?
0.507	2 10	EGA5.	$(E_c - E_t) =$	$= (0.24 \div 0.25) \text{ eV}$	•
0.23	-	-	` DLT\$´	no	?
0.23	$2 \cdot 10^{-17}$	-	TSC	no	?
$0.22 \div 0.25$	$8 \cdot 10^{-19}$	-	TSC	no	?
0.26	-	complex with V _{Ga}	TSC	no	?
0.24	-	-	TSC	no	?
0.23	-	intrinsic	TP	no	?
0.23 0.23	$1 \cdot 10^{-14}$	$V_{Ga}V_{As}$	DLTS	no	?
	$7 \cdot 10^{-15}$	$V_{Ga}V_{As}$	DLTS	no	
0.23		-	DLTS	yes	?
0.22	$\begin{array}{c} 2 \cdot 10^{-15} \\ 4 \cdot 10^{-16} \end{array}$	-	DLTS	no	?
0.258	4 · 10 10	- FCA6	DLTS	$yes = (0.43 \div 0.46) \text{ eV}$?
0.44	$1 \cdot 10^{-14}$		$(E_c - E_t) = TSC$		9
0.44	$9 \cdot 10^{-15}$	$V_{As}As_i, V_{As}$	TSC	no no	?
		-		no	•
0.43	$7 \cdot 10^{-16}$	intrinsic	DLTS	yes	?
0.44	$2\cdot 10^{-15}$	complex with V _{As}	DLTS	yes	?

0.44 $2 \cdot 10^{-15}$ complex with V_{As} DLTS yes ?

a) DLTS — deep level transient spectroscopy; TSC — thermally stimulated current; LDA — local density approximation; PA — positron annihilation techniques; TP — photoinduced transient spectroscopy; SCLC — space charge limited current

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CRediT authorship contribution statement) **Oleg Olikh:** Conceptualization, Methodology, Validation, Formal analysis, Investigation, Writing - Review & Editing, Visualization. **Petro Lytvyn:** Conceptualization, Methodology, Validation, Resources, Writing - Original Draft.

Data availability

The data that support the findings of this study are available from the corresponding author upon reasonable request.

Declaration of competing interest

The authors declare that they have no known competing financial interests or personal relationships that could have appeared to influence the work reported in this paper.

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